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SHEET 1 OF 1

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Form PTO 1449 U.S. DEPARTMENT OF COMMERCE (Modified) PATENT AND TRADEMARK OFFICE			ATTY DOCKET NO. 220033US2		SERIAL NO. 10/080,537			
				APPLICANT				
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Examiner, Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered, lockude copy of this form with next communication to applicant.								